

Radiation Hard/Tolerant Technologies (Pixel Detector)

- Introduction
- Radiation hardened technologies
- Rad-tol deep submicron technologies
- Summary

P.Jarron

G. Anelli, F. Anghinolfi, M. Campbell, F. Faccio, J. Kaplon, K. Kloukinas
E.Heijne, A. Marchioro, A. Paccagnella, A. Rivetti, W. Snoeys .. RD49



Radiation Hard Technologies

- History and trends
- Experience in HEP community
- Design aspect
- Yield



What technology for readout chips of Pixel detector

- Challenging specifications
- Technology choice driven by device and layout density (vital)
 - better with advanced CMOS technologies
- Present technology options
 - Use radiation hardened technology with “guaranteed” hardening
 - Use deep sub micron CMOS with radiation tolerant design



Brief History

- Impressive number of hardened technologies tested by HEP community since 10 years
 - UTMC, TCS-HSOI3HD, HARRIS...
 - Honeywell Bulk-0.8, Honeywell SOI-0.8, DMILL
 - and finally the Radtol deep submicron approach
- One mistake
 - hardening circuit = rad hard technology
- Issues
 - disappearance of rad hard technologies
 - hardened processes behind main stream technologies



In 1994: Perry COTS Initiative

- Buy more commercial technology/products
- Use industrial specifications
- Reduce costs

(1) Willam J.Perry, “*Specifications and standards - a new way of doing business*”
Memorendum, 1994.



Controversy: Is radiation hardened technology necessary

The screenshot shows a magazine page titled "SATELLITE SURVIVABILITY". The main heading is "The Commercial and Military Satellite Survivability Crisis". A sub-headline reads: "Whether it's natural radiation or radiation from a nuclear blast, can satellites survive? Unless you harden it, the Defense Nuclear Agency doesn't think so." Below this, a paragraph discusses the crisis, mentioning the Defense Nuclear Agency's concern over the impact of radiation on commercial and military satellites. The text continues to describe the challenges faced by satellite designers, particularly regarding radiation tolerance and power consumption. A table at the bottom left, titled "Table 1. Effects of space radiation on semiconductor devices", lists various effects like Total Ionizing Dose, Single Event Effects, and Displacement Damage, along with their descriptions. The right side of the page contains a column of text about radiation-tolerant microelectronics and their development.

From “defense Electronics” August 1995

“...Can Satellite survive? Unless you harden it, the defense Nuclear Agency doesn’t think so...”

consequence of post cold war DOD budget:

“20 rad-hard vendors in 1990, 4 today....

Source L. Dusseau/Montpellier



Radiation hardened technologies

- HEP has contact with 2 vendors
 - Honeywell: thin SOI RICMOSIV
 - TEMIC: thick SOI DMILL
- Other vendors
 - Lockheed Martin
 - Sandia Lab
 - Fabless vendors, SOS Peregrine
- Market driven by defense and Space
 - Defense: TID tens of krad
 - Space: TID hundreds of krad
 - Readout chips for pixel, TID up to 30 Mrad



Technologies for Pixel readout

	ALICE LHC-b	ATLAS	CMS	BTeV
Devices				
/cell	1500	250	125	
/cm ²	7.5 M	1.2 M	0.6 M	
Pixel cell size	420 μm x 50 μm	400 μm x 50 μm	150 μm x 150 μm	400 μm x 50 μm
Techno	I .25 μ	DMILL RicmosIV	DMILL RicmosIV	I .25 μ T .25 μ

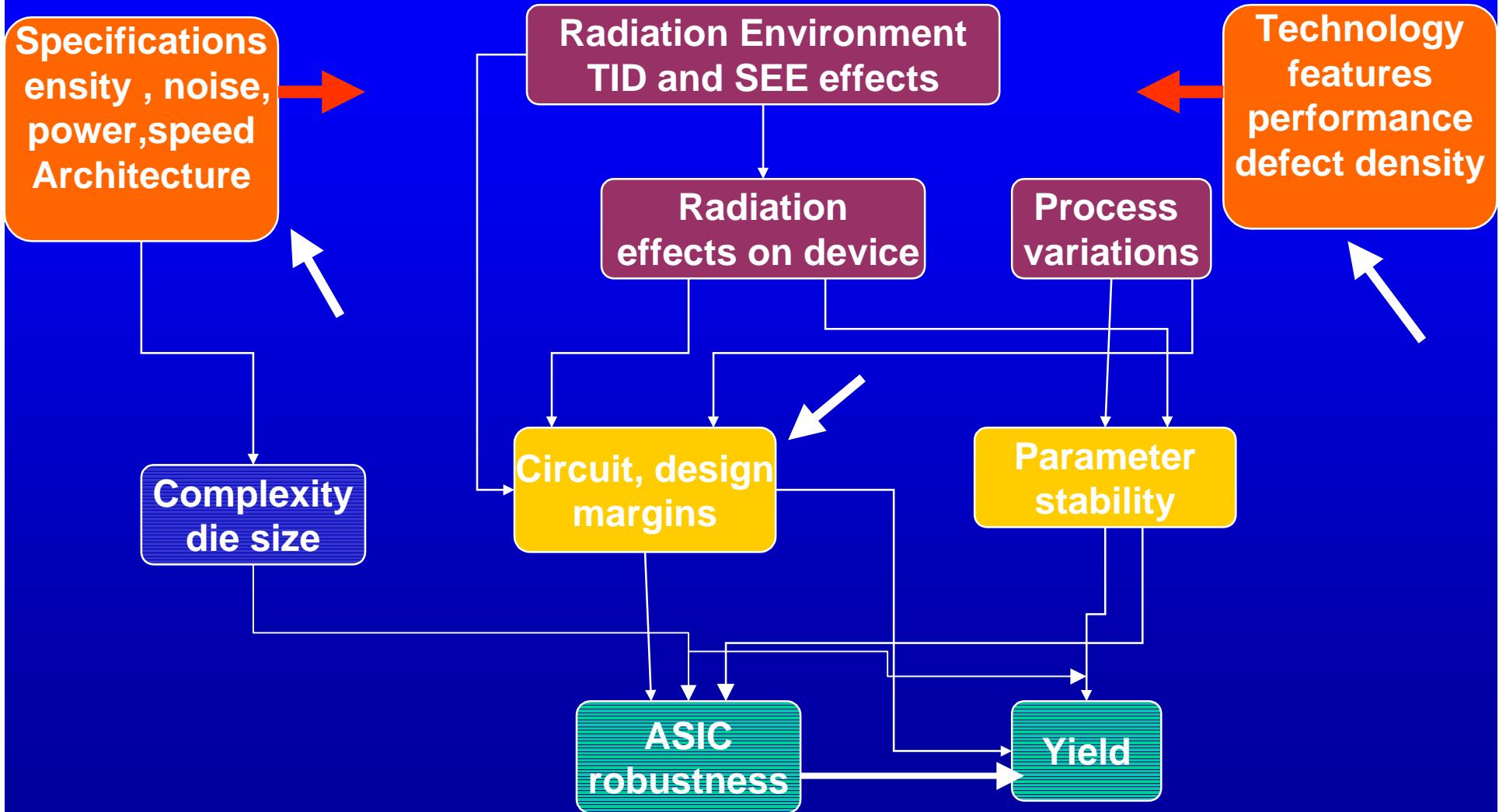


Rad hard Technologies: comments

- **Radiation hardening**
 - DMILL and RICMOSIV have radiation induced parameter shifts of devices “manageable”
 - Circuit design has a big impact
 - SEU : better with RICMOSIV (see CMS note 2000/036 R. Horisberger et al.)
- **Yield, a difficult story...**
 - rad hard technologies are low volume
 - special processes, not main stream
 - design margins not sufficient
- **Density**
 - RICMOSIV better density, 3 metal layers
 - 2 metal layers, lost silicon in DMILL



Design-process-yield-hardening



In production: good radiation hardening and yield

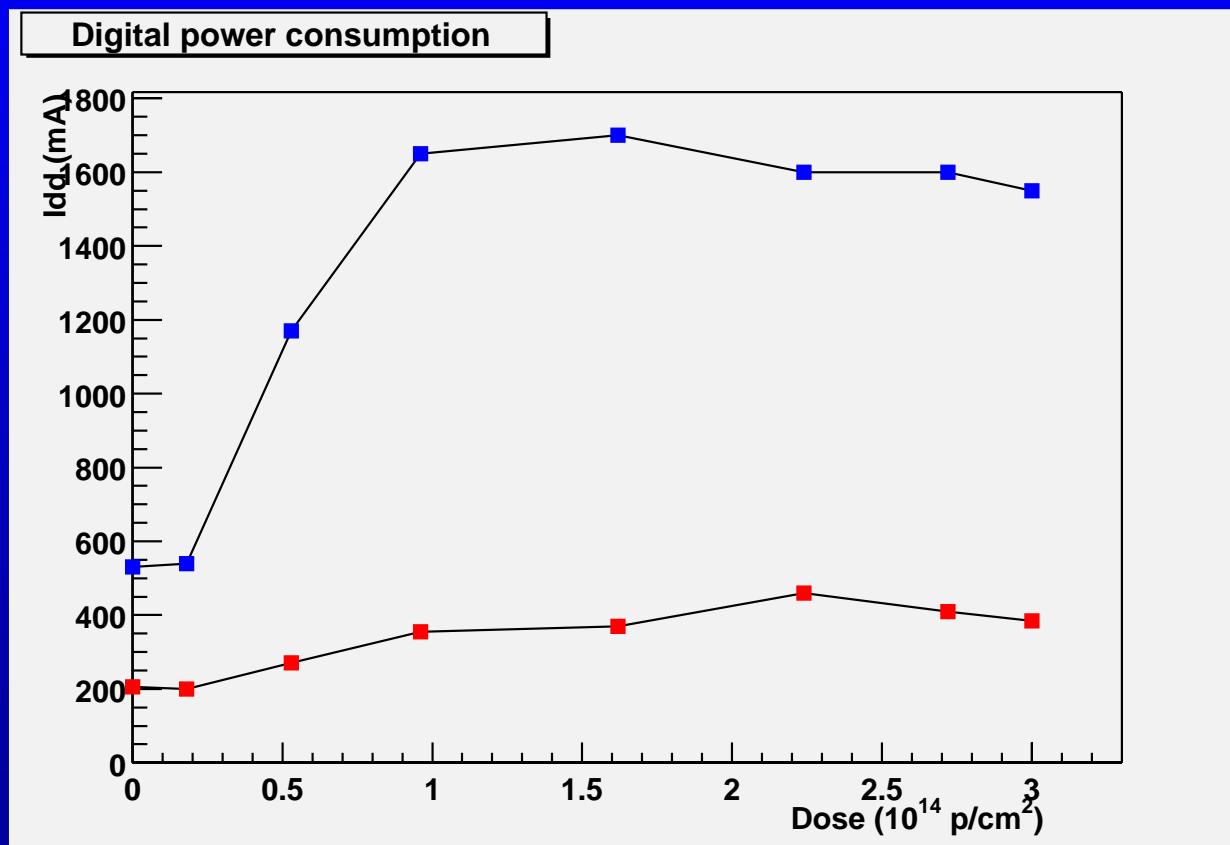
Pixel2000 Genoa 6 June 2000 P. Jarrou-CERN



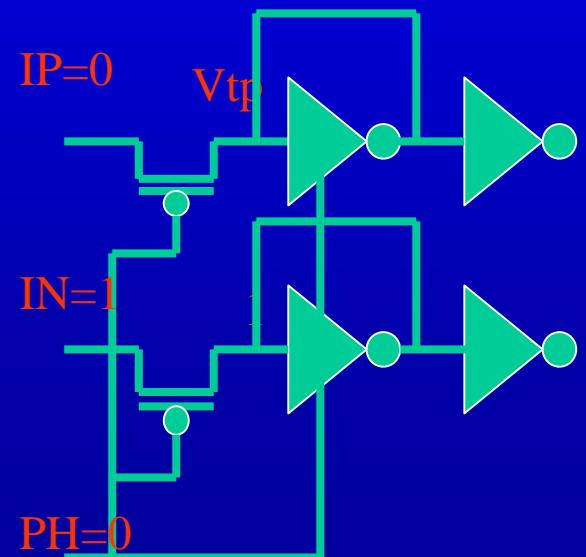
Hardening and design

Radiation response of 2 ABCD2T -DMILL lots

Problem with a modified transmission gate latch



Transparent mode
input switches on
inverters can be in
conduction regime



Yield of rad hard ASICs

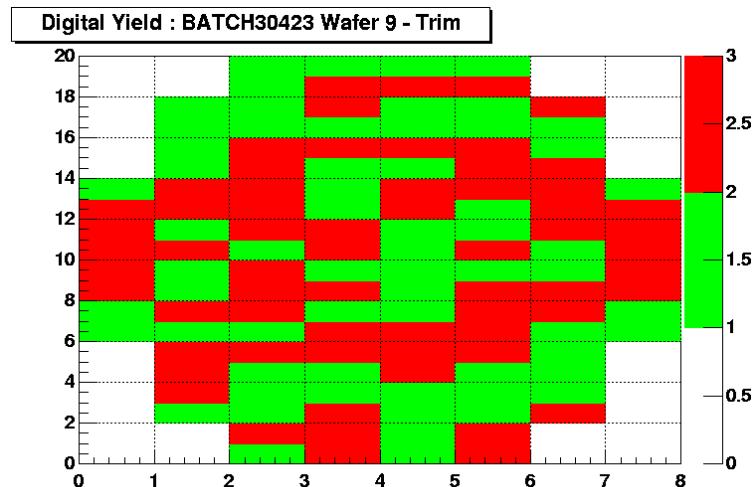
- Very few statistic
 - ATLAS: SCT ABCD2T , TRT DTMROC
 - yield 50% on the digital CMOS part for 50 mm² , 200 000 transistors, 27% with bipolar circuits
 - digital yield improved to 60%, and 37% in the back up lot
 - Pixel ATLAS
 - no yet conclusive
 - Pixel CMS
 - not yet available
 - SVX3:
 - see R. Yarema (Perugia), not yet solved



Yield: wafer mapping on DMILL



Digital tests - results from
30423 wafer #9



Map of the wafer with the ABCD chips tagged
according to the results of digital tests

- RED - no defect in the digital part
- GREEN - defect(s) in the digital part

ABCD2T wafer
J. Kaplon

Yield of CMOS circuit: 50%

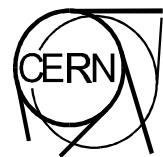
11-May-00

IV meeting on FE electronics for high resolution tracking detectors, PERUGIA May 16-19th, 2000

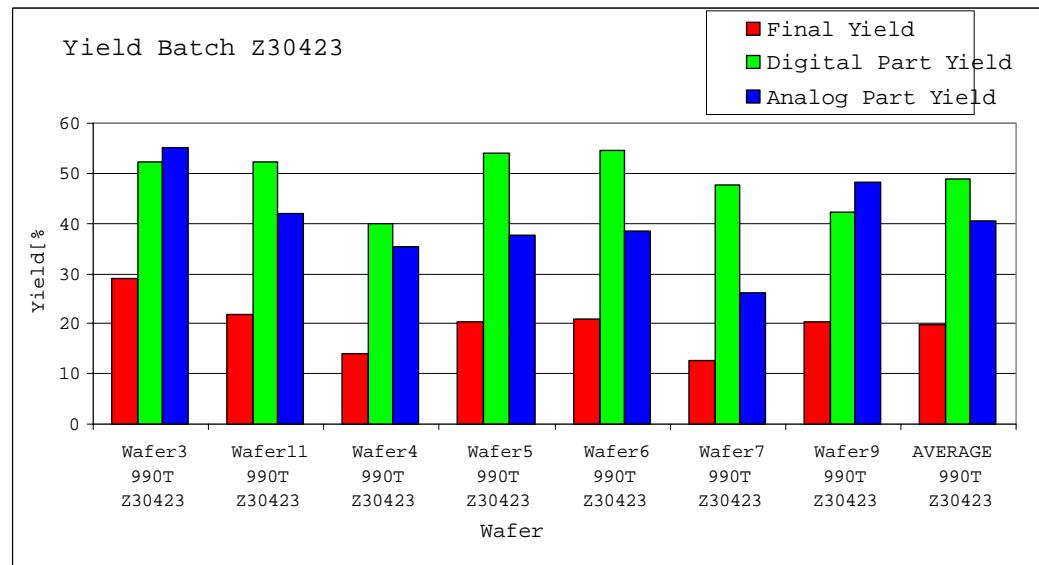


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Yield: DMILL wafer to wafer



Yield results



Yield for analogue part of the ABCD (based on calculation of defects in
analogue part for the ABCD2T for chips with no defects in the digital p
J. Kaplon

11-May-00

IV meeting on FE electronics for high resolution tracking detectors, PERUGIA May 16-19th, 2000

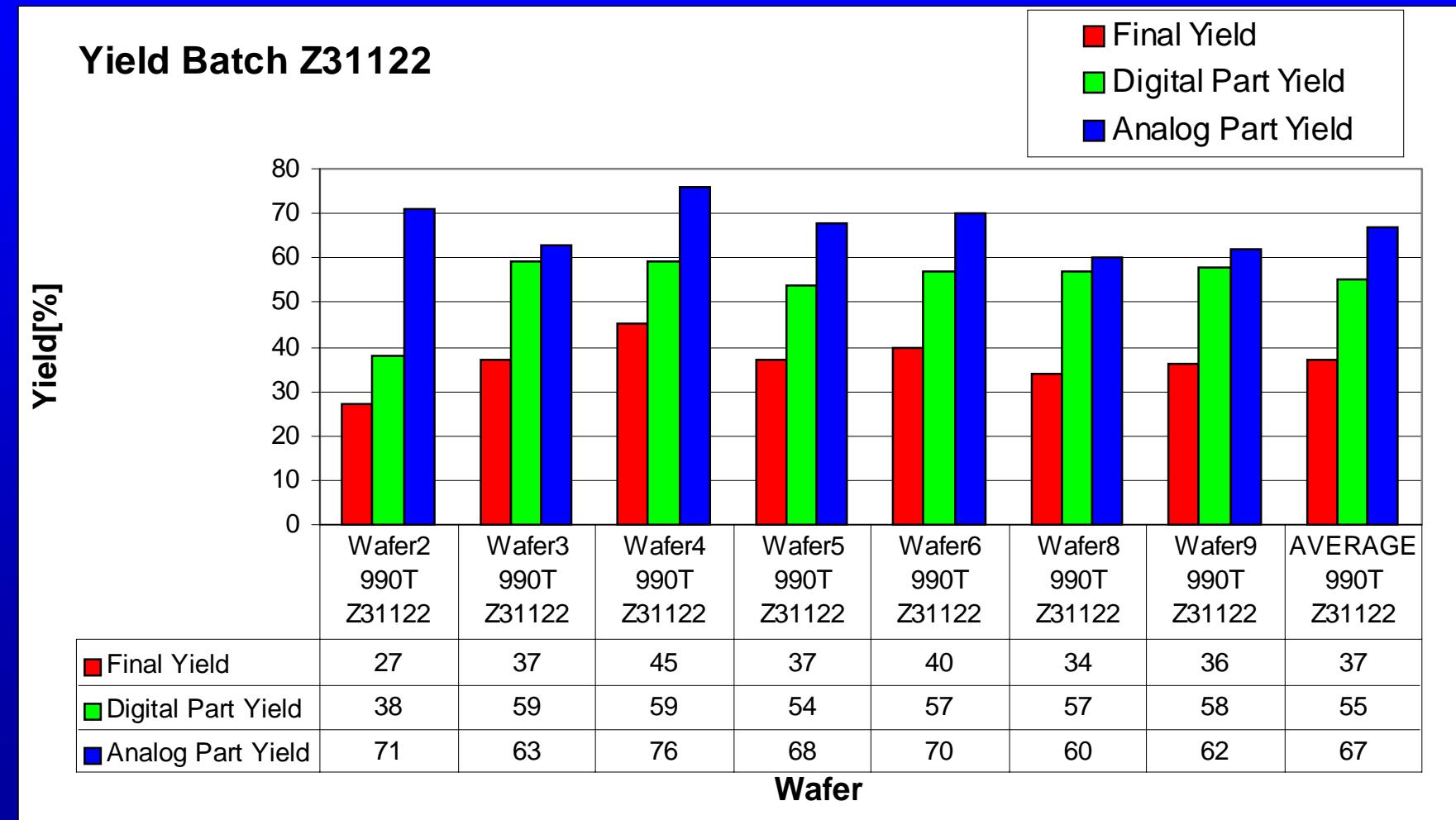


Pixel2000 Genoa 6 June 2000 P. Jarron-CERN

Yield of the back up ABCD2T lot

1st June 2000

Jan Kaplon



Deep submicron technologies

- Trends with device scaling
- Availability of vendors
- Radiation tolerance
- Issues

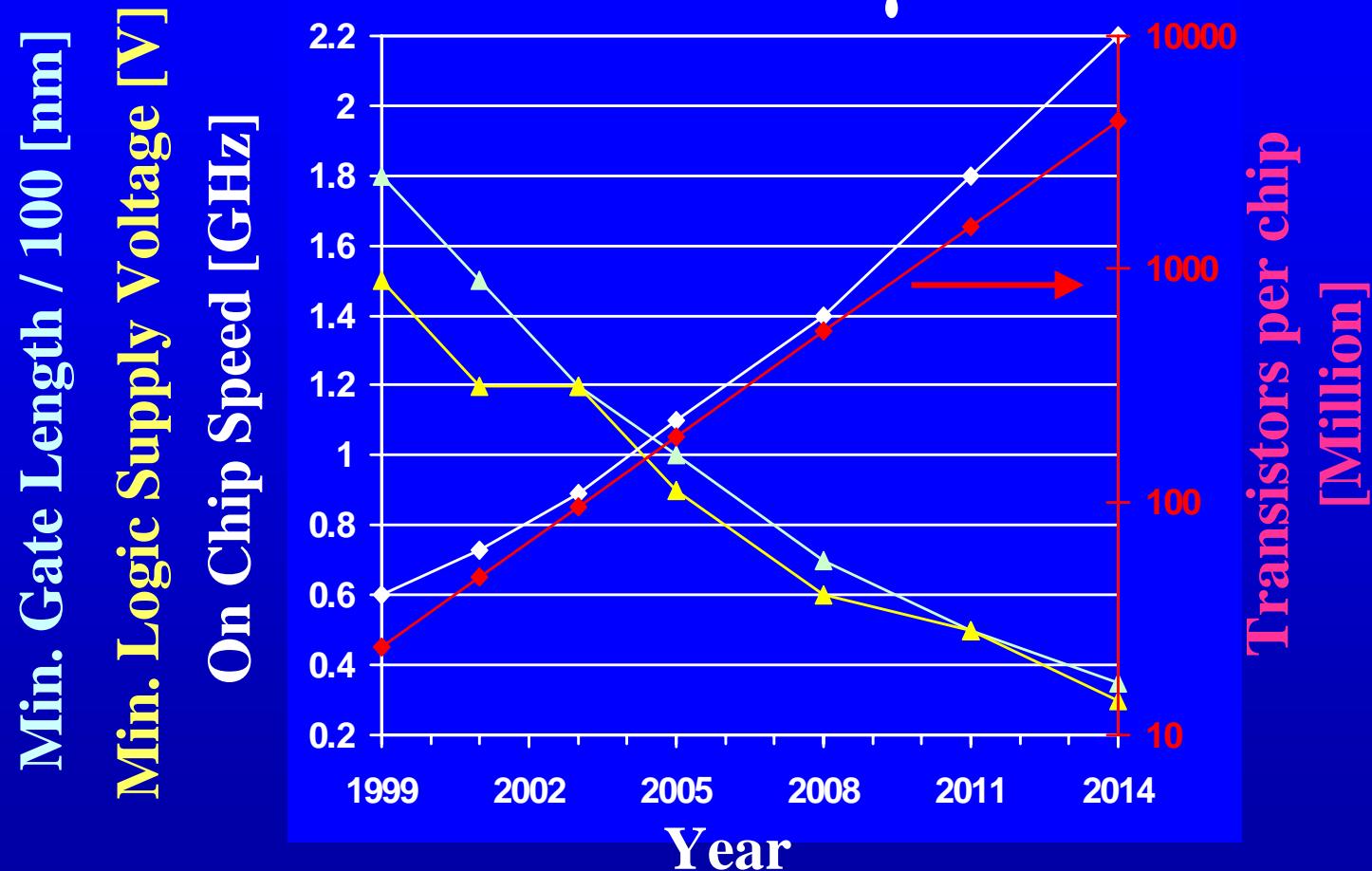


Motivation of the radiation tolerant approach in 0.25 (RD49)

- Radiation tolerance of thin gate oxide
 - rad-induced holes removal by e tunneling
 - very few rad-induced interface traps
- Features of deep sub micron technology
 - large scale integration - density
 - acceptable density of rad tol design
 - performance
 - speed, noise and matching are good
 - low power
 - main stream, large volume process
 - high yield, low cost
 - attractive for pixel readout chip



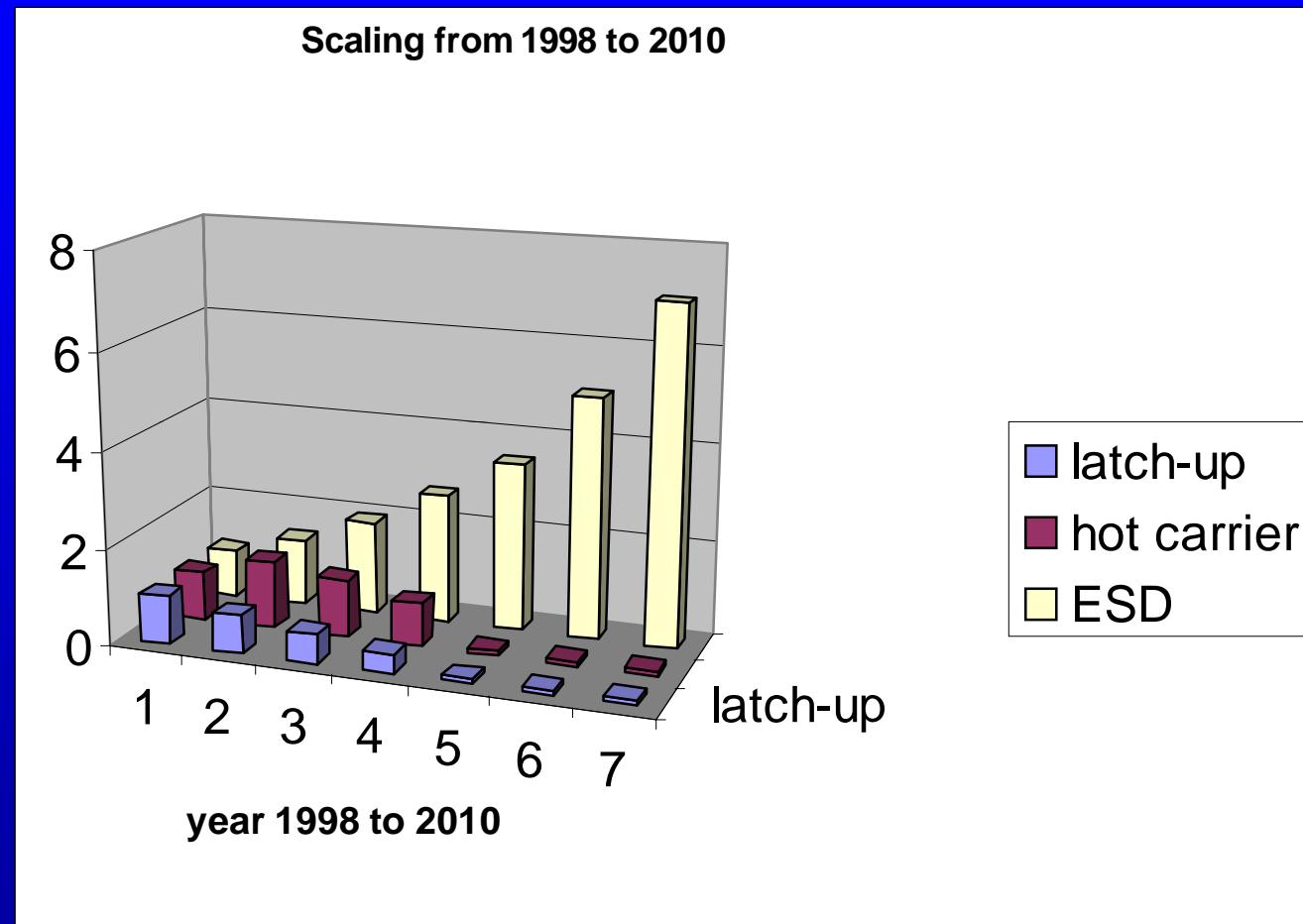
Technology scaling beyond CMOS 0.25μm



Compiled by G. Anelli Semiconductor Industry Association
The International Technology Roadmap for Semiconductors (1999 Edition)



Trends with device scaling

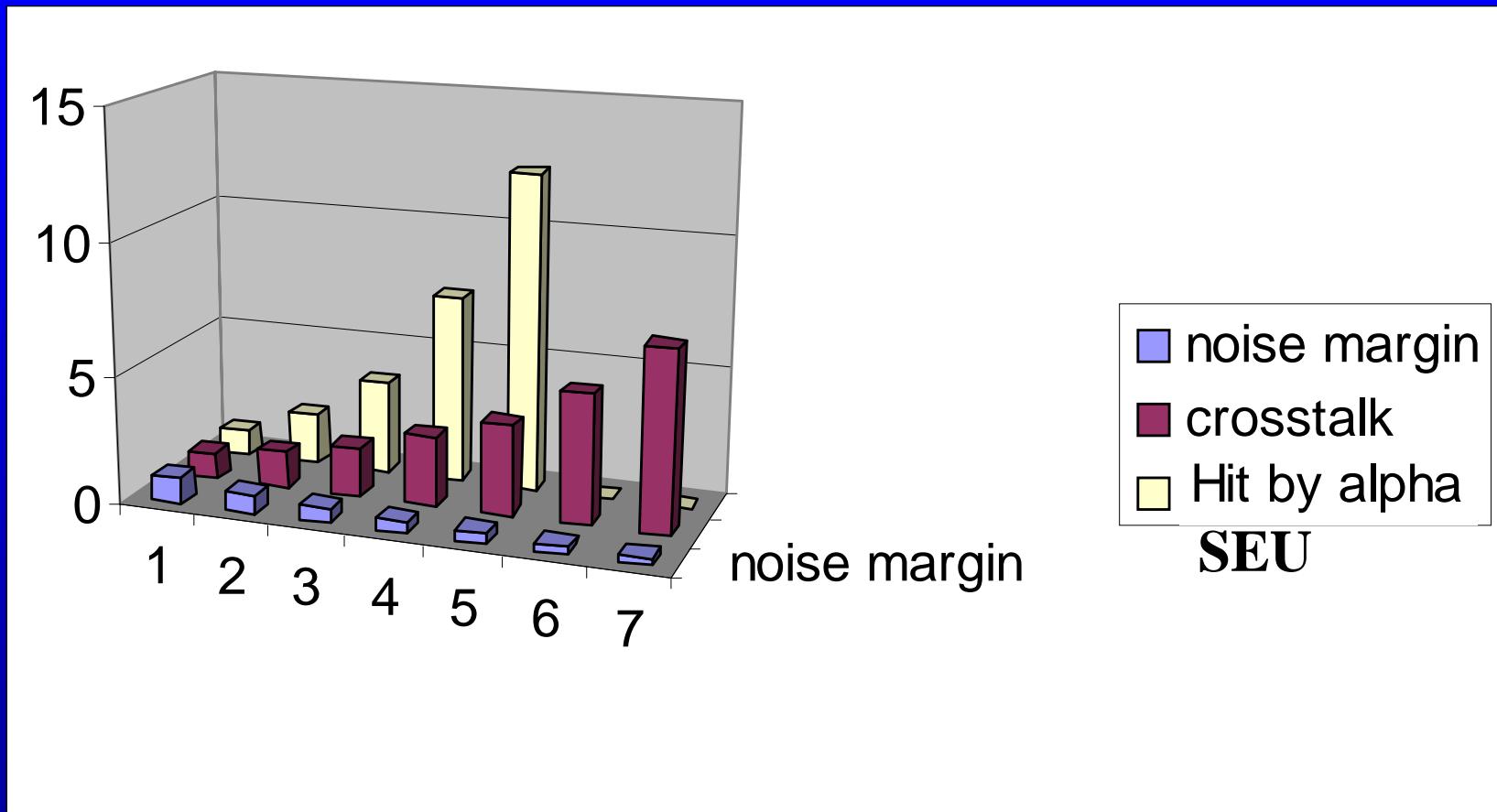


H. Veendrick, "Deep-Submicron CMOS ICs", Kluwer Academic Publishers, 1998



Pixel2000 Genoa 6 June 2000 P. Jarron-CERN

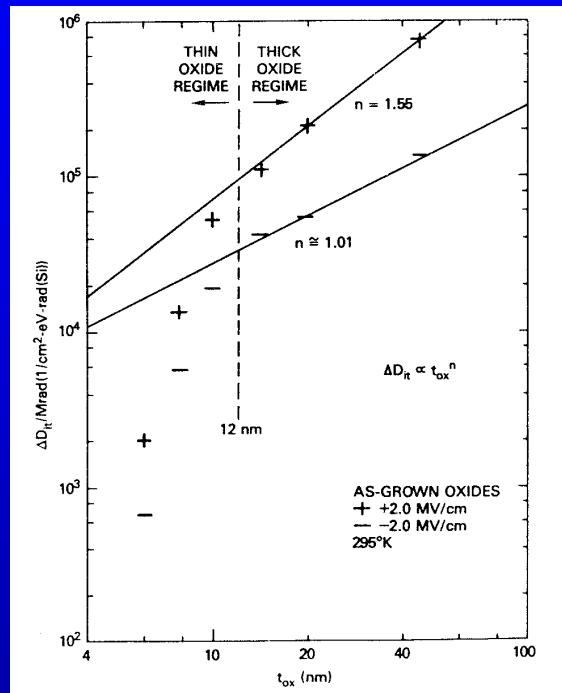
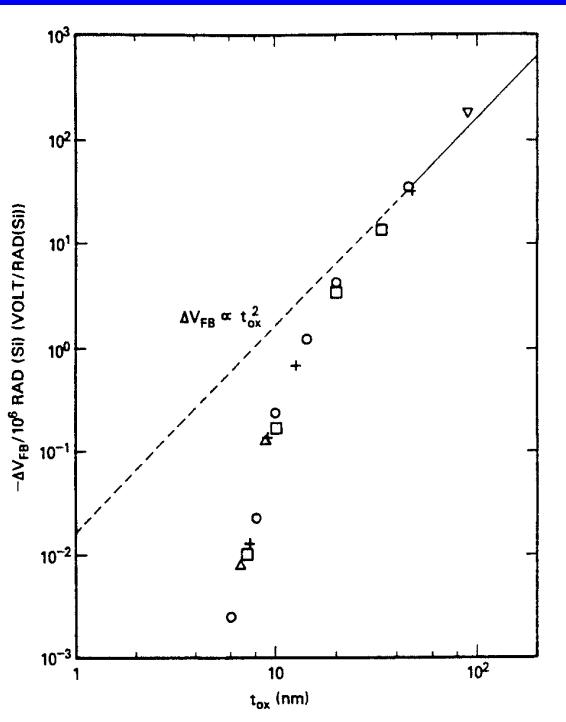
Trends devices scaling



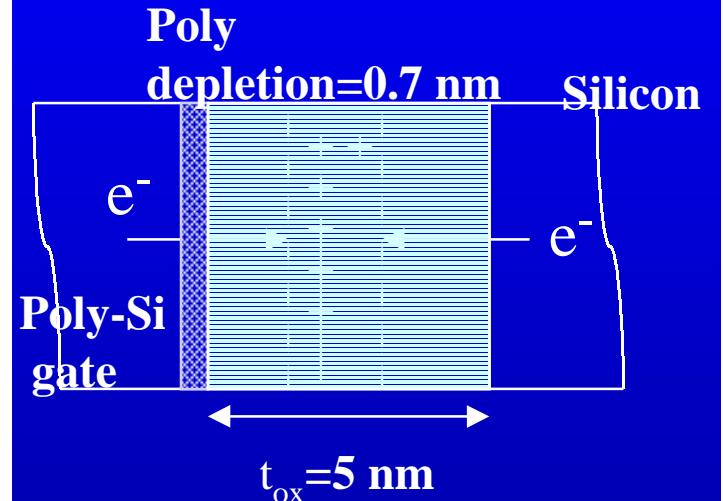
H. Veendrick, "Deep-Submicron CMOS ICs", Kluwer Academic Publishers, 1998



Radiation effects and t_{ox} scaling holes removal by e tunneling



Today 0.25 technology



Annealing $\propto \log t$
Front speed $\approx 0.2 \text{ nm/t-decade}$
Holes removal takes few hours in 5nm oxide

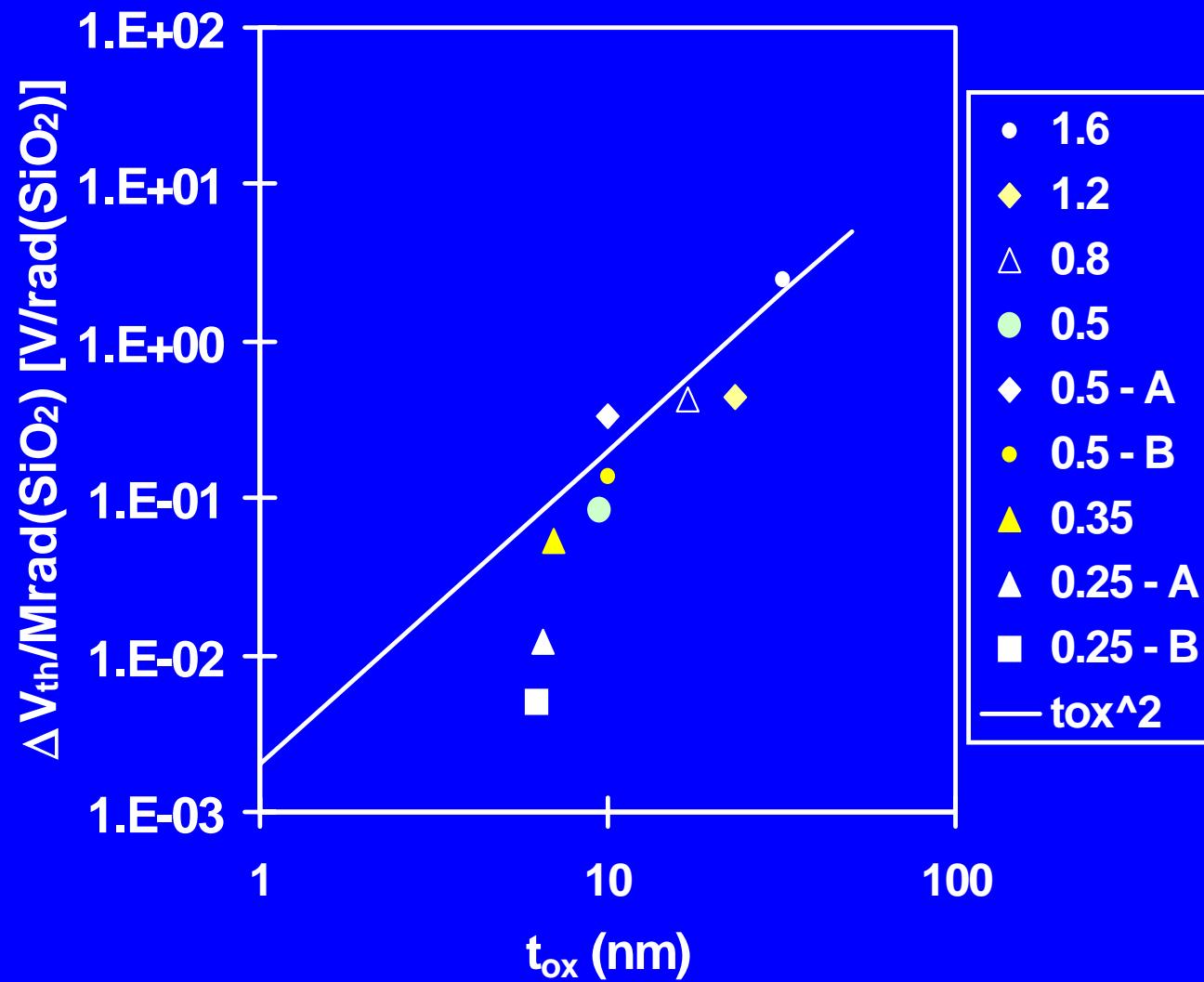
Vt-shift

N.S. Saks et al., IEEE TNS, Dec. 1984 and Dec. 1986

Interface traps



RD49 results on several technologies

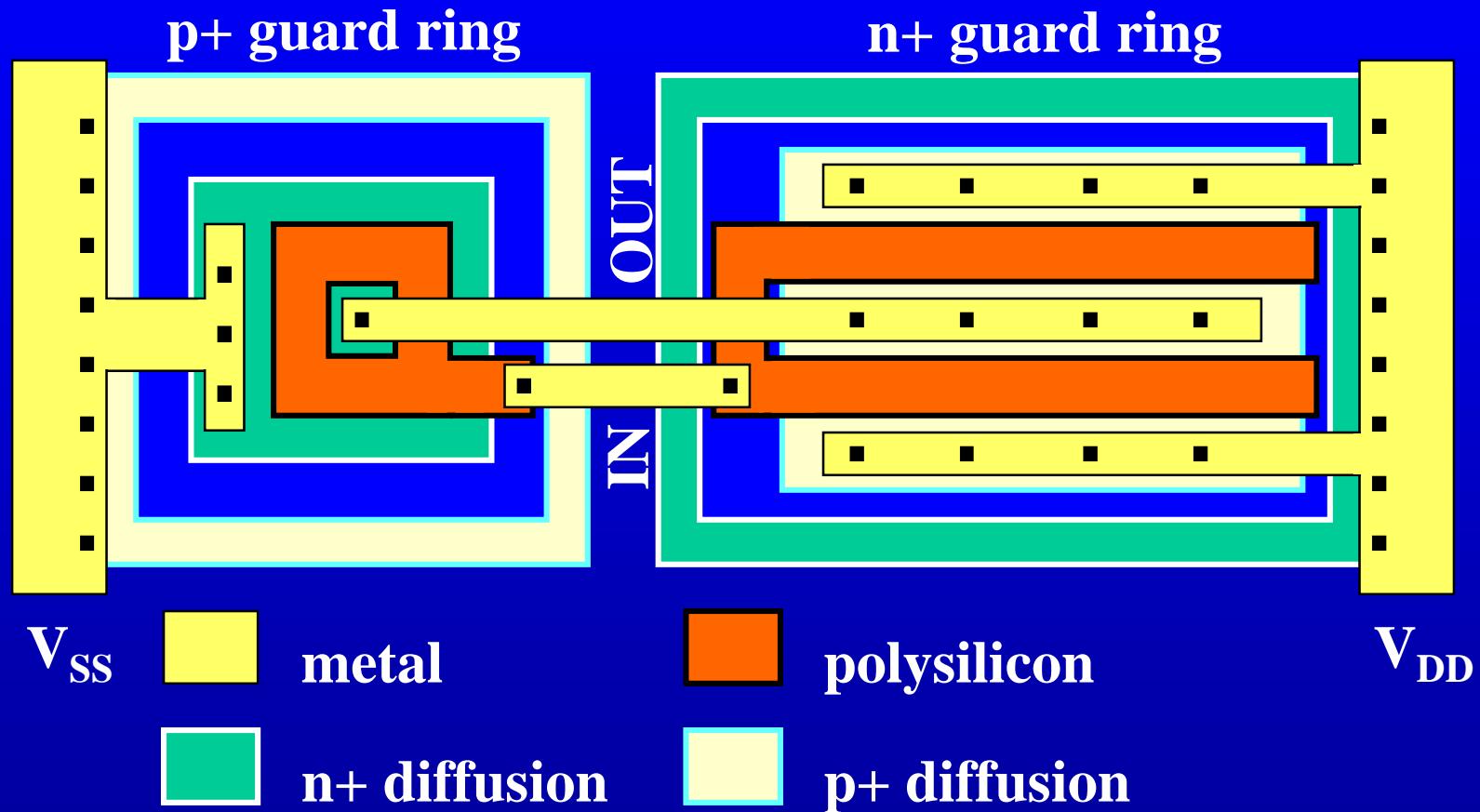


Conclusion of the recent book of T. Oldham

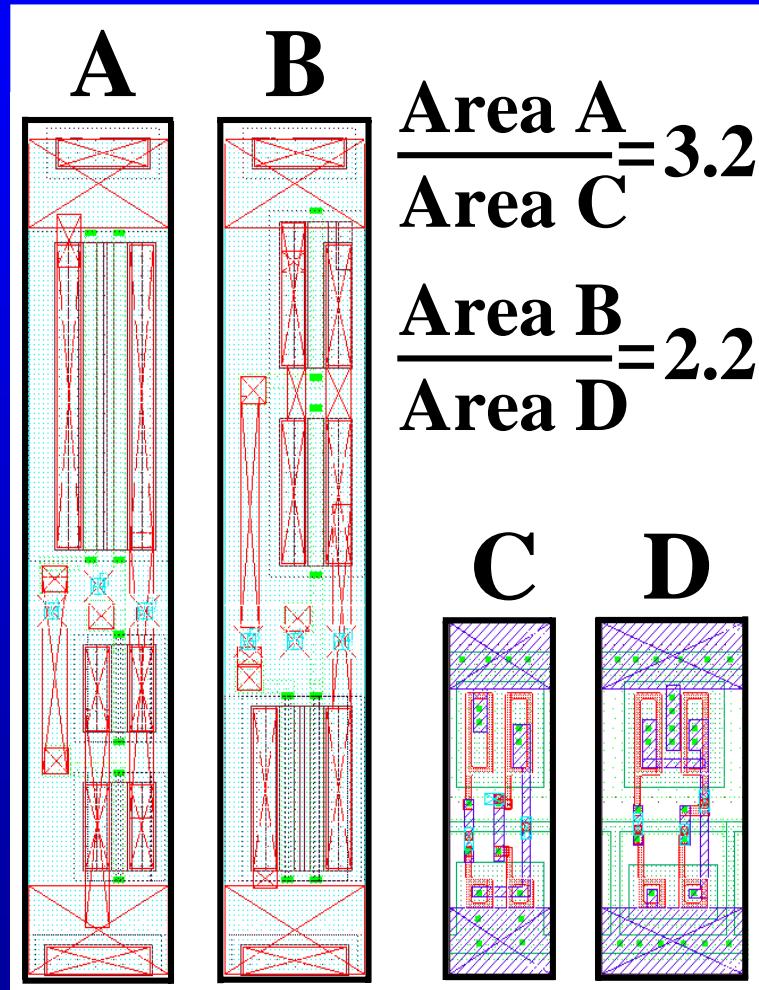
- Radiation Ionizing effects in MOS oxides : ISBN 981-02-3326-4
 - Update of Ma and Dressendorfer book published 3months ago
 - “... the general problem of radiation induced, gate oxide, threshold-voltage shifts may eventually be eliminated by the natural development of more advanced microelectronic technology with thinner oxides. At this point, the special radiation problems in electronics devices will be found in isolation structures.”
 - and SEU!!



Radiation tolerant layout approach - RD49



Density and speed from CERN radtol lib



A & B : 0.6 μm standard
C & D : 0.25 μm rad-tol

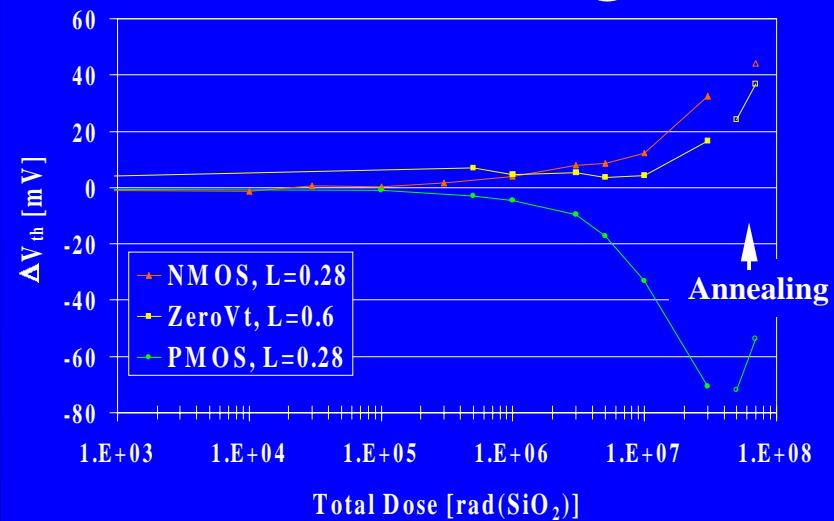
Inverter with F.O. = 1

	0.6 μm	0.25 μm
V_{DD} [V]	3.3	2
Delay [ps]	114	48
Pwr [$\mu\text{W}/\text{MHz}$]	1.34	0.14
Area [μm^2]	162	50

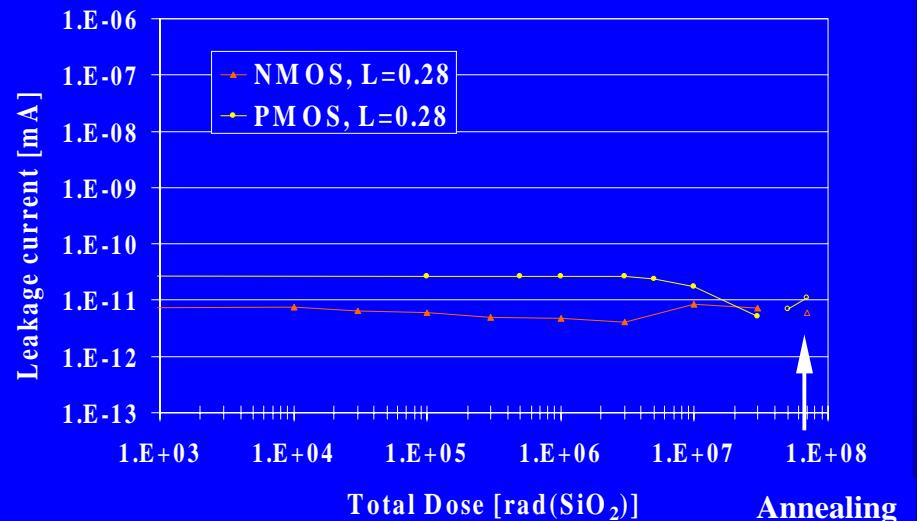


Total dose results up to 30 Mrad 0.25 μ m technology

Threshold voltage



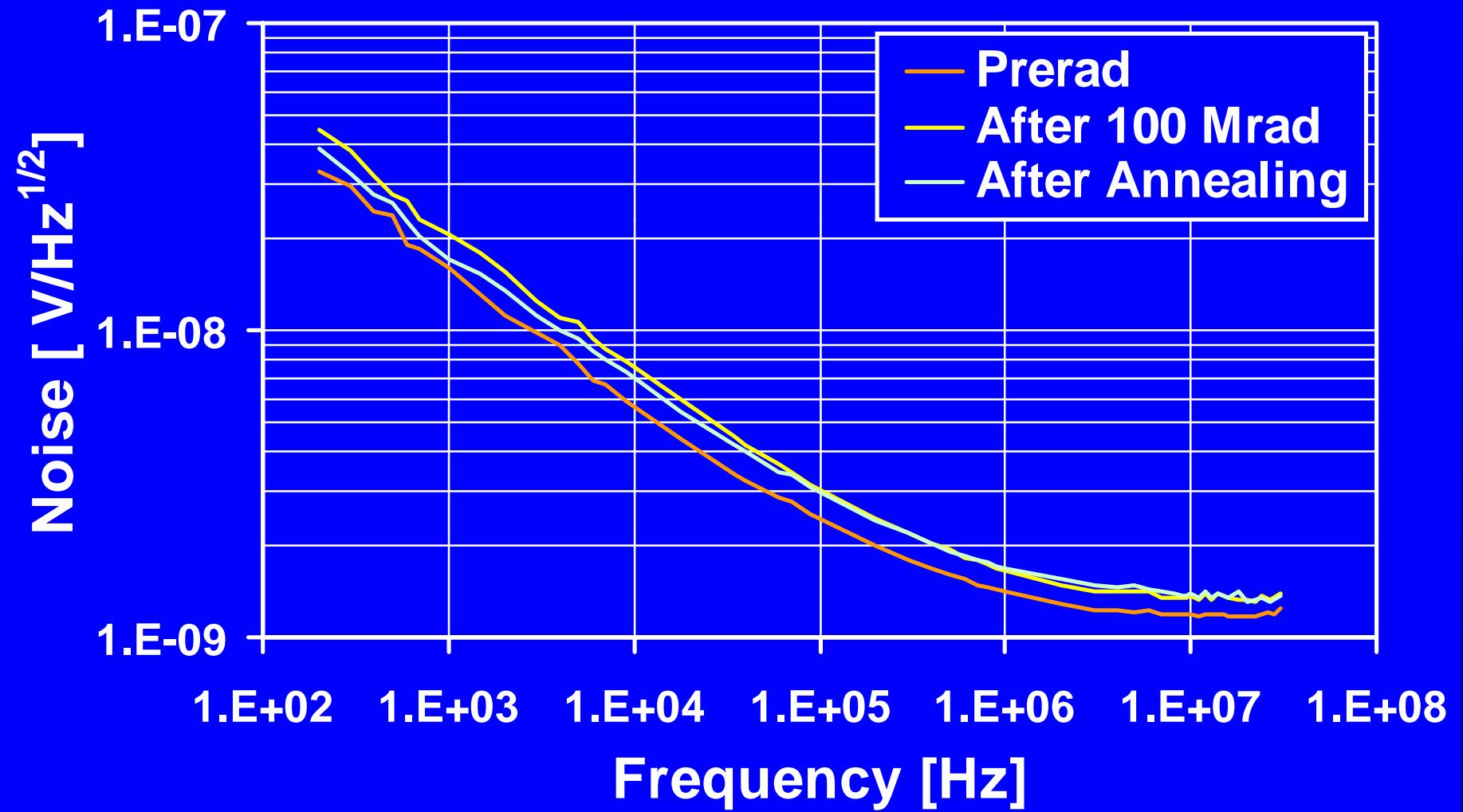
Leakage current



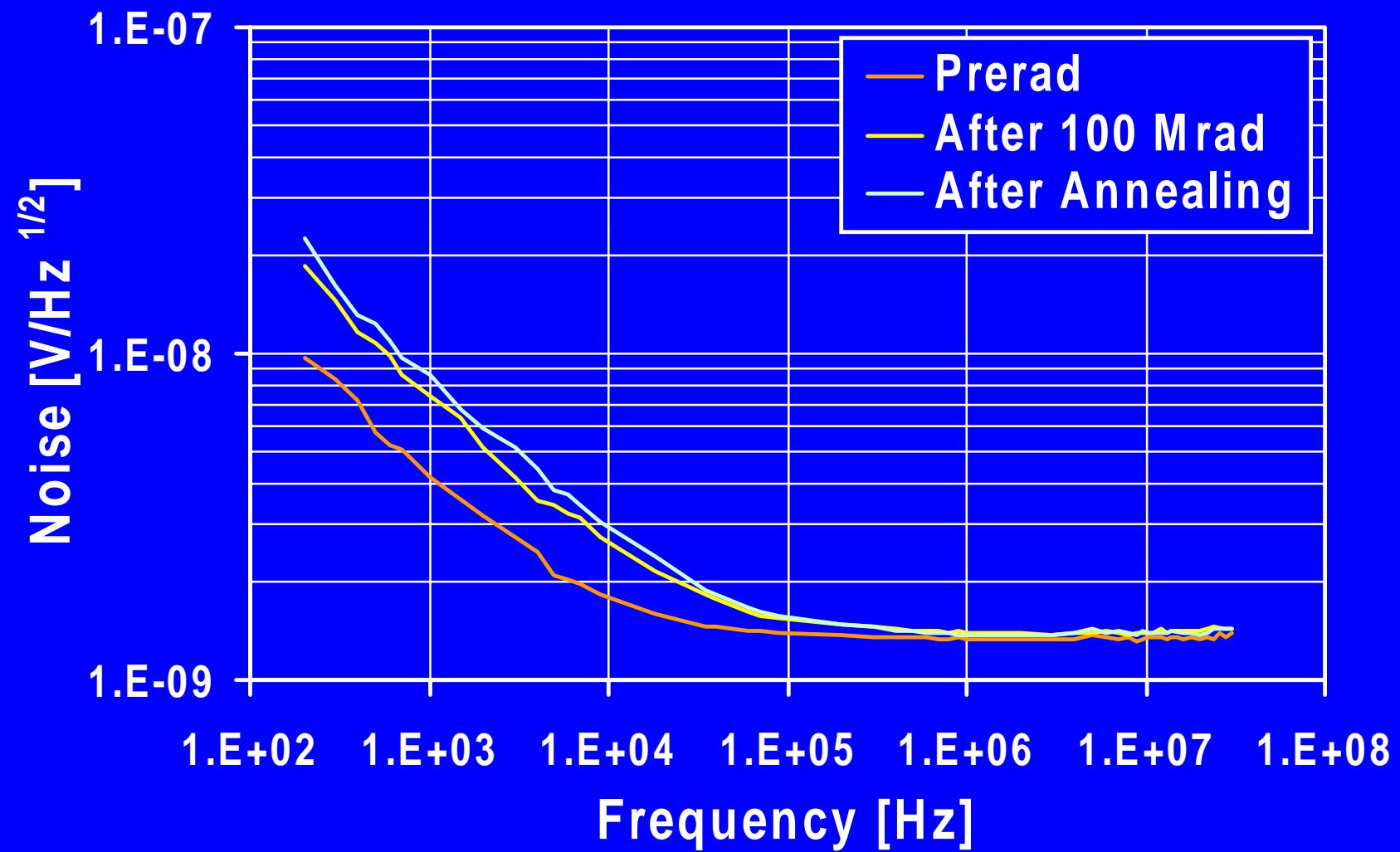
Mobility degradation:
< 6% NMOS
< 2% PMOS



N-channel noise spectrum



P-channel noise spectrum



0.25 μ m radtol HEP ASICs

- **Designed, fabricated and tested**
 - ALICE2, APV25, 10 Mhz 10bit ADC, 2V dynamic range analog memory, 1Gb/s serialiser, optical receiver, BTeV pixel readout +....
- **Full FE chip designed, in fabrication**
 - ALICE-LHC-b pixel readout
 - ALICE SDD readout
 - LHC-b silicon readout
 - +...
- **So far, positive results**



Access to DSM technologies

- $0.25\mu\text{m}$ ($V_t = 0.5\text{V}$)
 - CERN (MPW), RAL(support) radtol lib
 - IMEC UMC radtol lib
 - TSMC direct access, no radtol lib
 - CMP ST no radtol lib
 - MOSIS- TSMC
 - +....
- $0.18 \mu\text{m}$ ($V_t=0.4\text{V}$)
 - IMEC UMC radtol lib
 - CMP ST, possible radtol lib from ST
 - TSMC, no radtol lib
 - MOSIS TSMC
- $0.15 \mu\text{m}$ TSMC direct access



UMC 0.25 μ CMOS

▼ Base technology is the logic process (1 poly, 5 metal)

Well formation	Shallow-Trench (STI)
Isolation	Shallow-Trench (STI)
Poly Gate	N+, P+ Poly / Salicide
Gate Oxide	50 A
N/P MOS length	0.24 / 0.24 μ
Contact / Via size	0.32 / 0.4 μ
V _t N/P MOS	0.5 / -0.6 V
I _{dsat} N/P MOS	620 / 280 μ A/ μ m @ 2.5 V
Gate Delay/Stage	40/36 ps @ 2.5 V

Source : UMC

▼ Added with analog options

- high res poly
- capacitors : double poly or MM capacitors

UMC 0.18 μ CMOS - logic process

Key Process Features for the L180 Families	
Technology Node :	0.18um
Core Voltage :	1.8V
I/O Voltages :	2.5V/3.3V
Poly/Metal Layer :	1P6M (max. 6 metals)
Substrate/Well formation :	P-sub, Twin-Well
Isolation :	Shallow Trench Isolation
Gate Oxide thickness :	35A/50A(2.5V I/O)/65A(3.3V I/O)
Silicide :	Cobalt Salicide
ILD Planarization :	HDP/PE-PSG (CMP)
Interconnect :	W-plugs/AI metallization w/ top 2 layer Cu option
Passivation :	HDP/PSG/PESIN with Polyimide option
Poly pitch :	0.46um
Metal Pitch:	0.52um for metal 1
	0.56um for metal 2 to 5
	0.88um for top metal
Speed	
Ring Oscillator Delay :	27 ps
Leakage	
Standby Current (loff norm) :	0.01 nA/um

Source : UMC

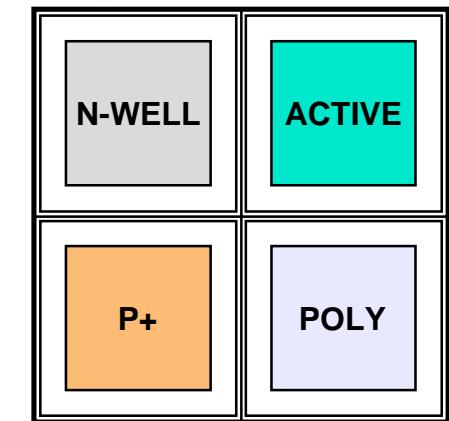
Multi Level Mask (MLM) techniques reduce the high mask costs

▼ Standard mask set is very expensive

- Full mask with one mask per design layer
- 60 k\$ @ 0.35 μ CMOS ... 300 k\$ @ 0.18 μ CMOS
- only possible for high volumes or "XXL" chips

▼ Multi Level Mask set

- 4 design layers per mask
- mask costs reduced by about 60%
- IC area limit : 9.5 x 9.5 mm
- ideal solution for
 - prototyping of "L" chips
 - pre-series
- Run start at any time



RETICLE (20 x 20 mm)
4 layers per reticle

▼ Available for Alcatel Microelectronics +ESM

Qualified Cell libraries and design kits are key to success

▼ Libraries

- Standard cell library (digital and analog) from foundry
- Available for all technologies
- For UMC 0.25µ CMOS : third party libraries from Virtual Silicon Technology

▼ Design kits

- for most of popular EUROPRACTICE software tools
 - Cadence, Mentor Graphics, Synopsys, Tanner, ...
- about 45 design kits

▼ FREE distribution by EUROPRACTICE on CD-ROM

- Customer signs NDA with IMEC and receives CD-ROM + key
- Layout stays at IMEC

Hardness of DSM technology

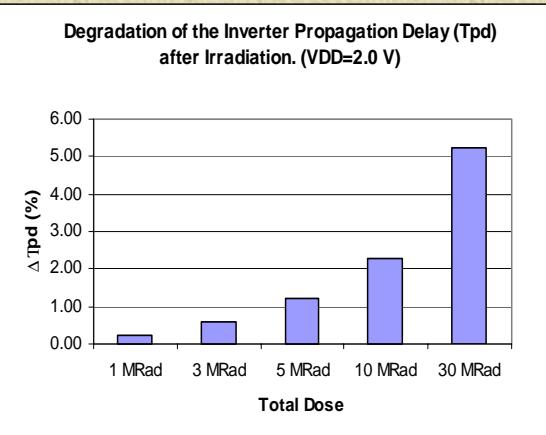
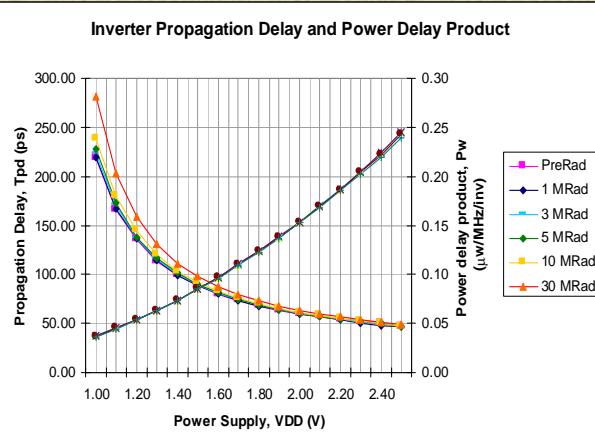
- No indication of TID problem with 0.25μ
- No evidence of hard failure
 - latch-up and single event gate rupture (see A. Paccagnella work and last RD49 report)
- SEU is an issue
 - not specific to DSM and technology dependant
 - mitigated by design for static FF and memory
- For technologies below 0.25μ
 - trends are positive for TID, latchup, not for SEU
 - trends of SEGR not well known
 - pay attention to thicker oxides used in I/O



CERN radtol 0.25 library: 30Mrad

Radiation Hardness Test

- # Total Dose Radiation Hardness Test
- # Test Circuit: Ring Oscillator (1001 inverters)



- # Test Conditions:
 - Dose Rate: 29KRad/min
 - Under bias (2.0V) during irradiation @ 25°C

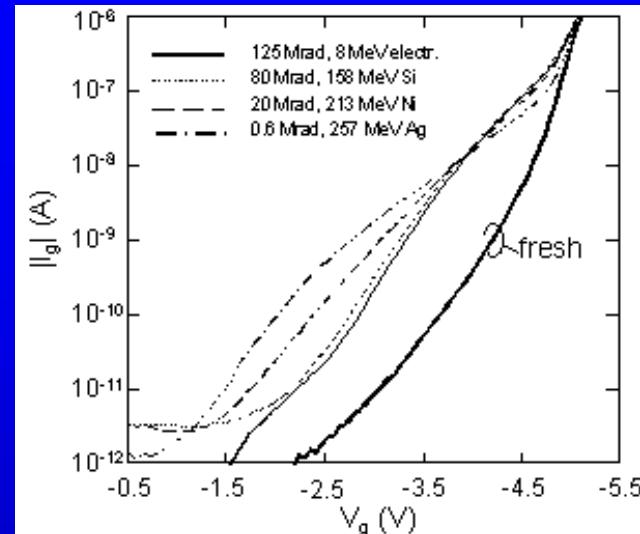
December 9, 1999

KLOUKINAS Kostas, CERN EP/MIC

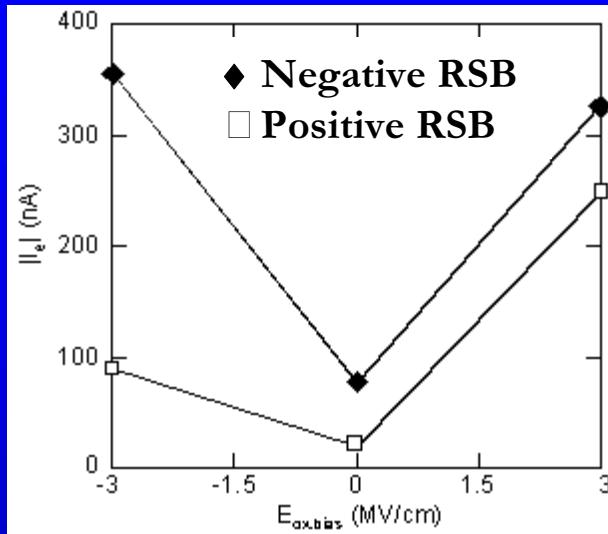
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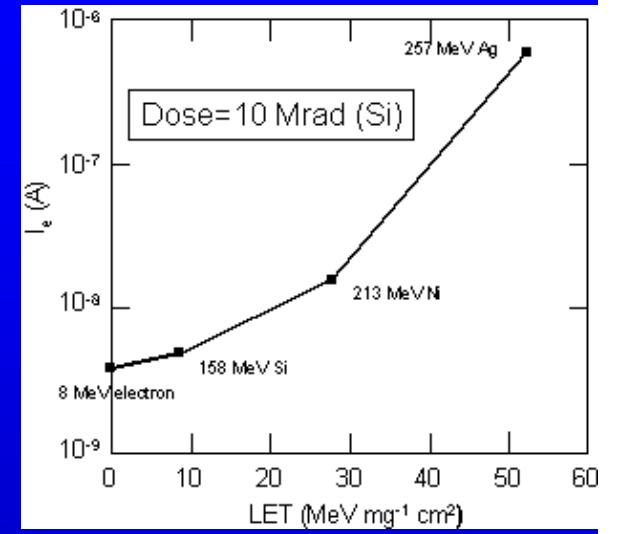
Rad induced gate rupture in 0.25 ?



Ig/Vg



Field dependence



LET dependence

2 Non-catastrophic phenomena observed

- *radiation induced leakage current RILC (TAT)*
- *Radiation induced Soft Burnout (heavy ions)*

A. Paccagnella's work on 1mm² 4nm gate structure

M. Ceschia, A. Paccagnella, A. Cester, A. Scarpa, and G. Ghidini, "Radiation Induced Leakage Current and Stress Induced Leakage Current in Ultra-Thin Gate Oxides NS-45, No. 6, pp.2375-2382, December 1998.

M. Ceschia, A. Paccagnella, S. Sandrin, G. Ghidini, J. Wyss, M. Lavale, and O. Flament "Low Field Leakage Current and Soft Breakdown in Ultra-Thin Gate Oxides After Heavy Ions, Electrons or X-ray Irradiation", RDAECs 99

L. Larcher, A. Paccagnella, M. Ceschia, and G. Ghidini "A Model of Radiation Induced Leakage Current (RILC) in Ultra-Thin Gate Oxides", IEEE Transactions on Nuclear Science, to be published



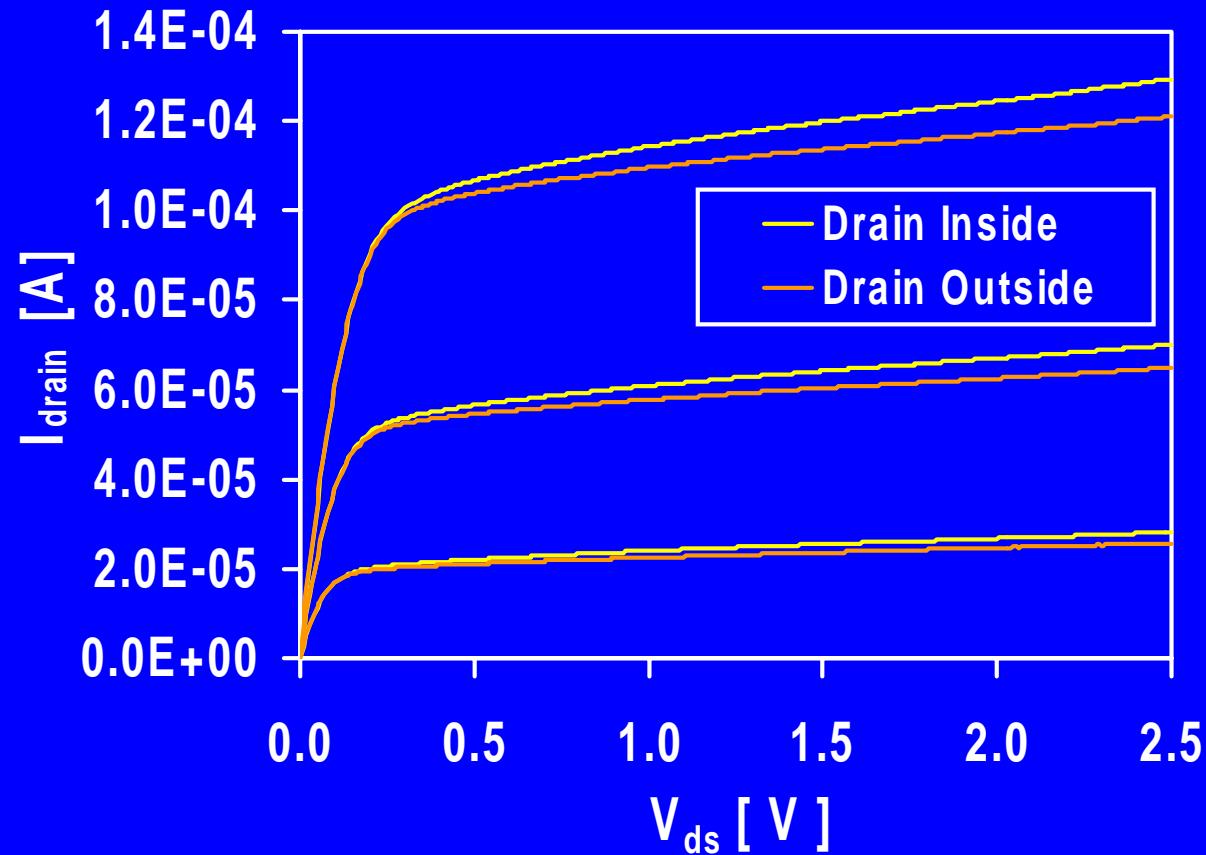
Radtol DSM: design issues?

- Radtol design rules
 - Minimum W/L=5 of enclosed n-channel
 - Big enclosed n-channel
 - Problem with long n-channel
 - Output conductance asymmetry
 - matching a bit worse for enclosed devices
- Technology
 - 1/f noise of short n-channel
 - CMOS switch limitation
 - SEU



Output Conductance

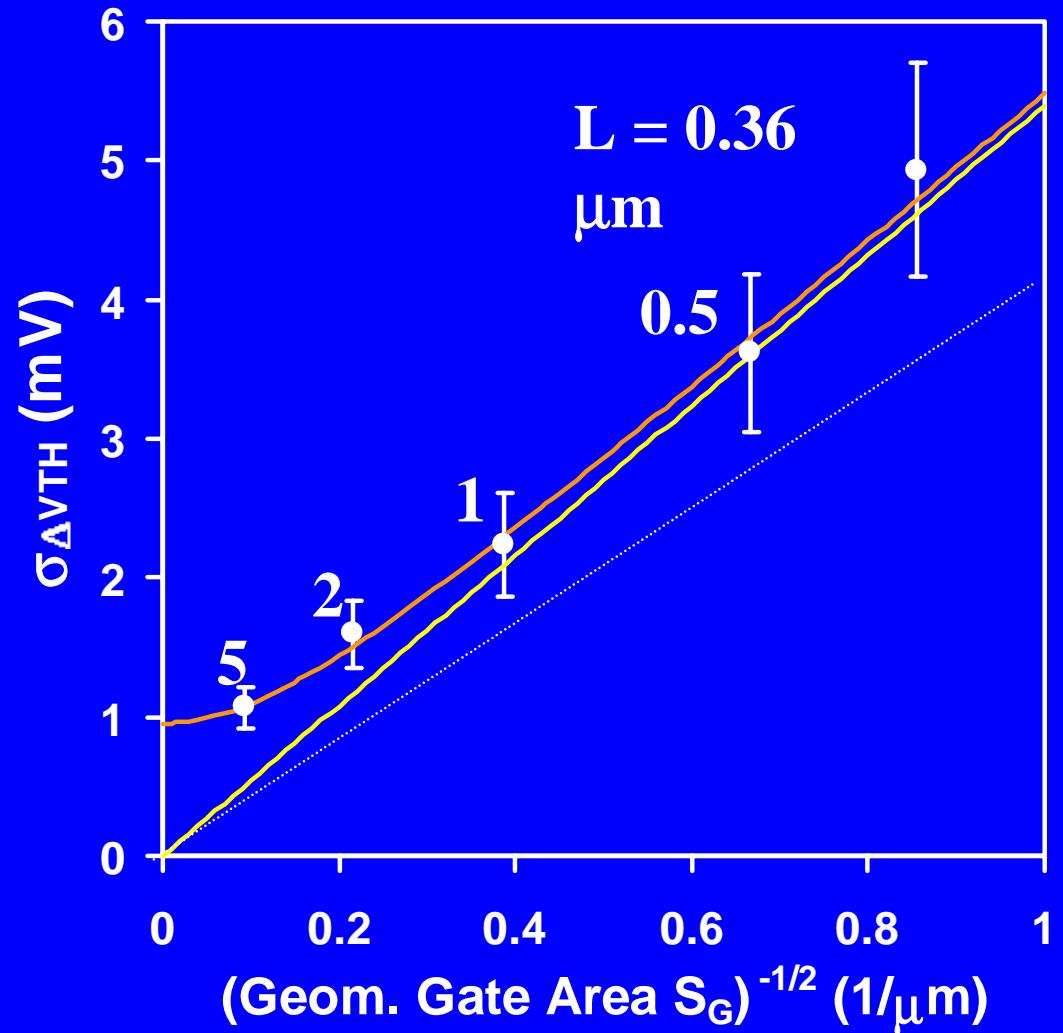
$$L = 0.28 \mu\text{m} \quad G_{DI} = 11.9 \mu\text{S} \quad G_{DO} = 9.6 \mu\text{S}$$



$L (\mu\text{m})$	$\Delta G/G_{DI}$
0.28	19 %
0.36	23 %
0.5	33 %
1	53 %
3	70 %
5	75 %



Matching of enclosed n-channel



$$\sigma_{\Delta P}^2 = \left(\frac{A_P}{\sqrt{S_G}} \right)^2 + \sigma_0^2$$

$$A_{V_{\text{th}}} = 5.4 \text{ mV}\cdot\mu\text{m}$$

$$\sigma_{0 V_{\text{th}}} = 0.95 \text{ mV}$$

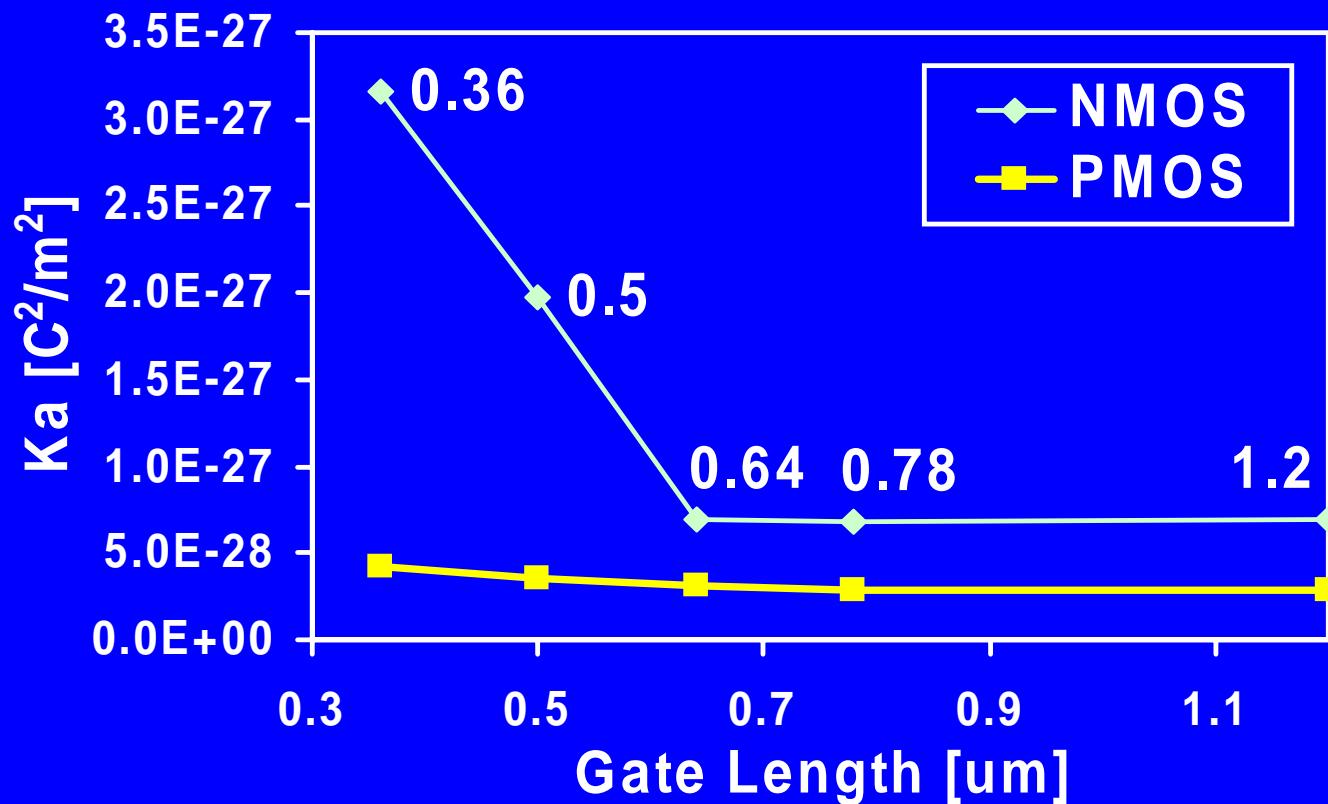
$$A_\beta = 1.5 \% \cdot \mu\text{m}$$

$$\sigma_{0 \beta} = 0.33 \%$$



1/f noise short n-channel

$$S_v = \frac{K_a}{C_{ox}^2 W L f^\alpha}$$

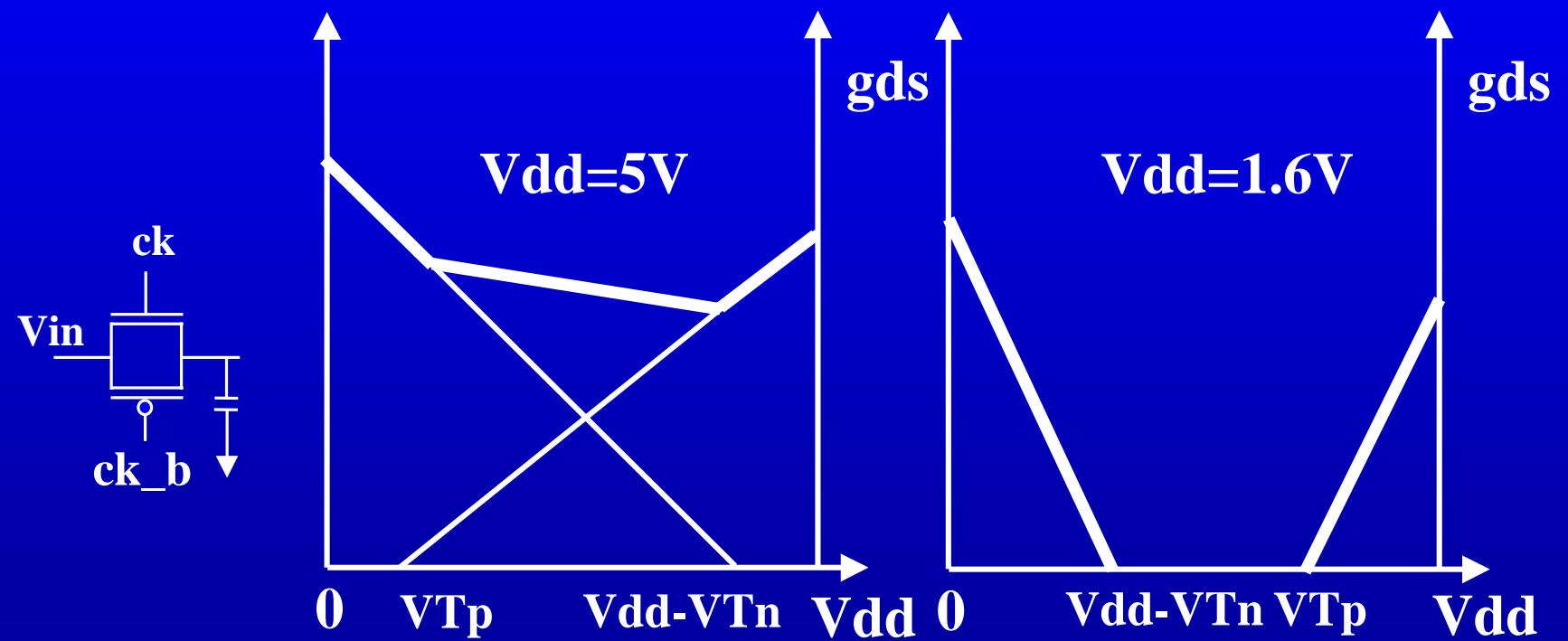


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SC circuits dynamic range

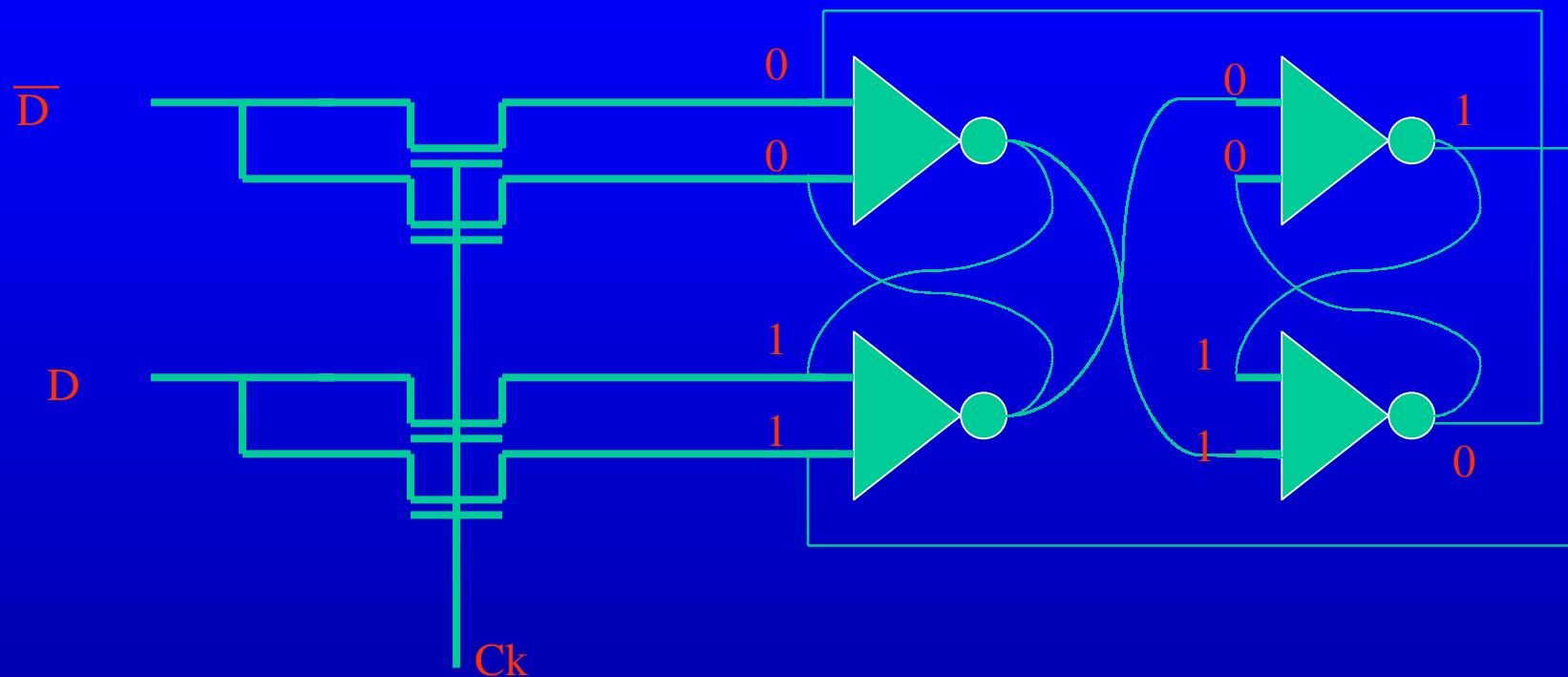


Summary of SEE for 0.25 radtol circuits RD49

- SEU test with Heavy ion: see F.Faccio's work
 - Static register
 - oversized design : upset rate **2x lower** than standard
 - C-overloaded design: upset rate **10x lower** than standard
 - dynamic register
 - much more susceptible than static register: **factor 300**
- SEU test with 60 MeV protons
 - static register no upset observed: $\sigma < 6 \cdot 10^{-15} \text{ cm}^2$
 - dynamic register upsets observed: $\sigma = 4 \cdot 10^{-13} \text{ cm}^2$
- No latch-up for ions of LET=89 MeV cm²/mg
- Risk of SEGR
 - no evidence with ALICE 2 test chip up to $9 \cdot 10^{14} \text{ pr/cm}^2$
 - RILC and RSB gate leakage, no evidence of hard burnout



SEU mitigation DICE memory cell principle



Patented by ST
Calin et, al.
NSS Vol43, Dec 96

- “2-input” inverter - gates disconnected
- Writing: load input FF, close inverters
- Storage: input FF biased by second FF
- SEU: no memory upset for one node upset



SUMMARY

- Rad hard technologies
 - Yield and hardness reasonable for ABCD2T and DTMROC, see yield on pre production
 - more problems with pixel readout chips
 - Issues: design margins and process stability
- Rad tolerant 0.25 μm CMOS
 - radtol approach compatible with all standard deep submicron technologies - present and future
 - impressive hardening level and device density
 - superb results obtained on several circuits
 - attractive for new development of pixel readout chips

